



IFW  
PATENT  
Atty. Dkt. AMAT/8245/DSM/BCVD/JW

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Wang, et al.

Serial No.: 10/800,112

Filed: March 12, 2004

Confirmation No.: 8920

For: Method of Depositing an  
Amorphous Carbon Film for  
Metal Etch Hardmask  
Application

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

§ Group Art Unit: 1763

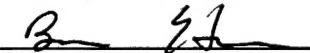
§ Examiner: Unknown

### CERTIFICATE OF MAILING

37 CFR 1.8

I hereby certify that this correspondence is being deposited on  
March 23, 2005, with the United States Postal Service as First  
Class Mail in an envelope addressed to: Commissioner for  
Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

March 23, 2005  
Date

  
Signature

### PRELIMINARY AMENDMENT

Prior to examination, please amend the above-identified application as follows.  
Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/8245/BKH, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Specification** begin on page 2 of this paper. **The Pending Claims** are reflected in the listing of claims which begins on page 3 of this paper. **Remarks** begin on page 7 of this paper.